Chinastandards.org

CCS L95

SJ

INDUSTRY STANDARD OF THE PEOPLE'S REPUBLIC OF CHINA

SJ 21130-2016

General specification for plasma etching machines

等离子体刻蚀机通用规范

(English Translation)

Issued by: Ministry of Industry and Information Technology

Preview: page 1 of 3 shown, 13 in the full document. Complete English PDF, instant download:
https://chinastandards.org/standards/sj-21130-2016

Chinastandards.org

Table of Contents

[Preview only]
1 Scope
2 Normative References
2.1 Terms
3 Terms and Definitions
4 Overview
4.1 General requirements
5 Technical Requirements
6 Calibration conditions
6.1 Environmental conditions
6.2 Measurement standards and other equipment
7 Calibration items and calibration methods
7.1 Calibration Items
7.2 Calibration method
8 Expression of calibration results
9 Recalibration interval

1 Foreword

SJ 21130-2016 is issued by Ministry of Industry and Information Technology.

The SJ prefix, without a suffix, marks a mandatory standard: within its scope, compliance is required.

The document runs to 13 pages in English translation.

2 Scope Preview

SJ 21130-2016 is filed under Chinese Standard Classification L95, in the field of electronic components and information technology.

This catalogue holds 1,191 other SJ standards without an ICS number.

In this catalogue, SJ standards carry edition years from 1965 to 2021.

Preview: page 2 of 3 shown, 13 in the full document. Complete English PDF, instant download:
https://chinastandards.org/standards/sj-21130-2016

3 About this standard

Sector: Electronics Industry Standard

Issued by: Ministry of Industry and Information Technology

English translation: about 13 pages (approximate)

Chinese original: about 20,232 characters

4 Related standards

Standards on related subjects:

GB/T 28159-2025 - Electronic grade phosphoric acid

SJ/T 11794-2022 - Test method for unbonded lithium of cathode materials used in lithium ion battery

SJ/T 11795-2022 - Test method for determining magnetic impurity content of electrode materials in lithium ion batteries

SJ 21128-2016 - General specification for horizontal plasma chemical vapor deposition equipment (PECVD)

SJ 21129-2016 - General specification for metal organic chemical vapor deposition equipment (MOCVD)

SJ 21131-2016 - General specification for reactive ion etching machines

5 Classification and status

Chinese Standard Classification (CCS): L 95

Prefix SJ: mandatory standard.

Preview: page 3 of 3 shown, 13 in the full document. Complete English PDF, instant download:
https://chinastandards.org/standards/sj-21130-2016